

## Patent Abstracts of Japan

PUBLICATION NUMBER : 2001189371  
 PUBLICATION DATE : 10-07-01

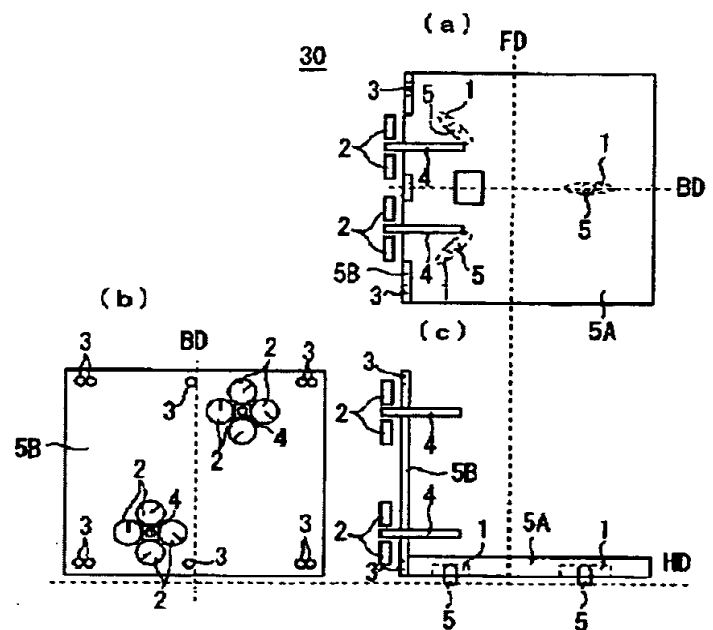
APPLICATION DATE : 31-05-00  
 APPLICATION NUMBER : 2000162788

APPLICANT : SEMICONDUCTOR LEADING EDGE  
 TECHNOLOGIES INC;

INVENTOR : FUJII ATSUHIRO;

INT.CL. : H01L 21/68

TITLE : LOAD PORT ADJUSTING TOOL,  
 FOUP-MEASURING TOOL, FOUP  
 WAFER PLANE MEASURING TOOL,  
 KINEMATIC PIN SHAPE EVALUATING  
 TOOL, KINEMATIC PIN POSITION  
 EVALUATING TOOL, AND  
 ADJUSTMENT/MEASUREMENT/EVALUATION  
 METHOD USING THEM



ABSTRACT : PROBLEM TO BE SOLVED: To smooth the transfer of a substrate on the FIMS surface of a load port when manufacturing a semiconductor, improve switching reliability of a FOUP switching mechanism, and improve compatibility and switching reliability of an interface door.

SOLUTION: The position measurement mechanism for measuring a registration pin position on an FIMS surface, a position measurement mechanism for measuring the registration pin hole position of an FOUP door, a distance measurement mechanism for measuring distance from the FIMS surface to a front virtual reference surface, and the like are combined, thus obtaining a load port adjusting tool, an FOUP-measuring tool, and the like.

COPYRIGHT: (C)2001,JPO